

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
 ( Not for submission under 37 CFR 1.99)

Application Number	10598943
Filing Date	2006-09-15
First Named Inventor	Peng-Fei Fu
Art Unit	1762
Examiner Name	Unknown
Attorney Docket Number	071038.00102

U.S. PATENTS							<a href="#">Remove</a>
Examiner Initial*	Cite No	Patent Number	Kind Code <sup>1</sup>	Issue Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines where Relevant Passages or Relevant Figures Appear	
	1						

If you wish to add additional U.S. Patent citation information please click the Add button. [Add](#)

U.S. PATENT APPLICATION PUBLICATIONS							<a href="#">Remove</a>
Examiner Initial*	Cite No	Publication Number	Kind Code <sup>1</sup>	Publication Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines where Relevant Passages or Relevant Figures Appear	
	1	20020137870	A1	2002-09-26	Crivello		

FOREIGN PATENT DOCUMENTS							<a href="#">Remove</a>	
Examiner Initial*	Cite No	Foreign Document Number <sup>3</sup>	Country Code <sup>2</sup> i	Kind Code <sup>4</sup>	Publication Date	Name of Patentee or Applicant of cited Document	Pages, Columns, Lines where Relevant Passages or Relevant Figures Appear	Ts
	1	WO99/26112	WO		1999-05-27	DHAL, et al		<input type="checkbox"/>
	2	WO9212183	WO		1992-07-23	Crivello		<input type="checkbox"/>

If you wish to add additional Foreign Patent Document citation information please click the Add button [Add](#)

NON-PATENT LITERATURE DOCUMENTS							<a href="#">Remove</a>
---------------------------------	--	--	--	--	--	--	------------------------

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
( Not for submission under 37 CFR 1.99)

Application Number	10596943
Filing Date	2006-09-15
First Named Inventor	Peng-Fei Fu
Art Unit	1762
Examiner Name	Unknown
Attorney Docket Number	071038.00102

Examiner Initials*	Cite No	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc), date, pages(s), volume-issue number(s), publisher, city and/or country where published.	Ts
	1	CRIVELLO ET AL., "The Synthesis, Characterization, and Photoinitiated Cationic Polymerization of Silicon-Containing Epoxy Resins" Journal of Polymer Science Polymer Chemistry Edition, 1990, Vol 28, pages. 479-503, XP 000141356.	<input type="checkbox"/>
	2	CRIVELLO ET AL., "The UV Cure of Epoxy-Silicone Monomers, Polymeric Materials Science and Engineering, 1989, pages. 217-227, XP009035836.	<input type="checkbox"/>
	3	LABIANCA ET AL., "High Aspect Ratio Resist For Thick Film Applications", Advances in Resist Technology and Processing XII, Spie, 1995, Vol. 2438, pages 846-852, XP002437324.	<input type="checkbox"/>
	4	MATSUI ET AL., "Room-temperature nanoimprint and nanotransfer printing using hydrogen silsequioxane", Journal of Vacuum Science & Technology B: Microelectronics Processing and Phenomena, American Vacuum Society, March 2003, Vol. 21, No. 2, pages 688-692, XP012009626.	<input type="checkbox"/>
	5	PFEIFFER ET AL., "Reactive Polymers - a Route to Nanoimprint Lithography at Low Temperatures", Proceedings of Spie, Spie, 2003, Vol 5037, pages 203-210, XP-002297929.	<input type="checkbox"/>
	6	PFEIFFER ET AL., "Multistep profiles by mix and match of nanoprint and UV lithography", Microelectronic Engineering, 2001, Vol. 57-58, pages 381-387, XP004302289.	<input type="checkbox"/>
	7	SUN XIAOYUN ET AL., "Multilayer resist methods for nanoimprint lithography on nonflat surfaces", Journal of Vacuum Science & Technology B: Microelectronics Processing and Phenomena, American Vacuum Society, 1998, Vol. 16, No. 6, pages 3922-3925, XP012007311.	<input type="checkbox"/>
	8	International Search Report, International Application No. PCT/US2005/019340, dated June 29, 2007.	<input type="checkbox"/>

If you wish to add additional non-patent literature document citation information please click the Add button

**EXAMINER SIGNATURE**

Examiner Signature	Date Considered
--------------------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through a citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
( Not for submission under 37 CFR 1.99)

Application Number	10596943
Filing Date	2006-09-15
First Named Inventor	Peng-Fei Fu
Art Unit	1762
Examiner Name	Unknown
Attorney Docket Number	071038.00102

<sup>1</sup> See Kind Codes of USPTO Patent Documents at [www.USPTO.GOV](http://www.USPTO.GOV) or MPEP 901.04. <sup>2</sup> Enter office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>3</sup> For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>4</sup> Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. <sup>5</sup> Applicant is to place a check mark here if English language translation is attached.